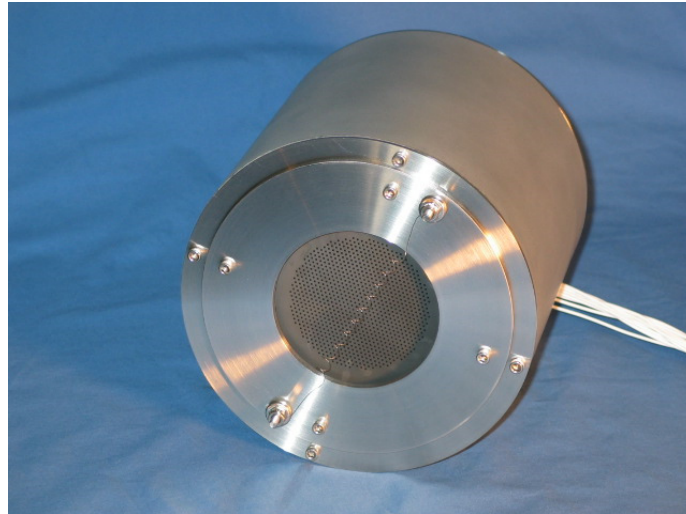




# plasma process group

## 8 cm DC Ion Beam Source



### Features

- **Filament Cathode**
- **Filament Neutralizer or Plasma Bridge Neutralizer (PBN)**
- **Flange or Internal Mounting**
- **Versatile Power Range**
- **Easy Maintenance**

### Applications

- **Sputter Deposition**
- **Etching**
- **Ion Beam-Assisted Deposition**
- **Materials Research**
- **Ion Thruster Research**

### Description

Plasma Process Group offers an 8 DC ion beam source for use in surface modification, etching and deposition applications. The 8 cm source is ideal for small research systems or small scale manufacturing systems.

Our 8 cm ion sources have filament cathodes and can operate with a filament neutralizer or a PBN. Both conditions will operate with typical process gases such as argon or nitrogen.

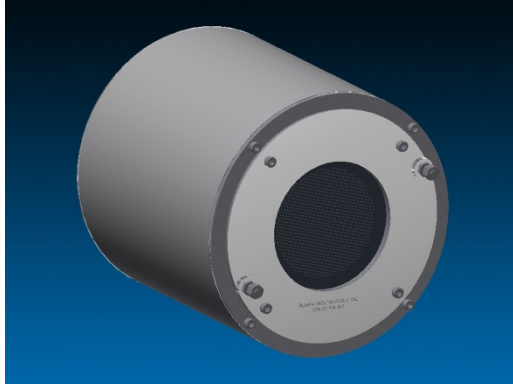
The 8 cm Source can be mounted to a flange for fixed beam geometry, or internally mounted for adjustable orientation. Our ion sources were designed with maintenance in mind, using fewer parts than previous generations of ion sources, making installation and maintenance much easier.

This source is a flexible option for any facility and is a reliable and high quality component.

*Whether you're in a research or production environment, Plasma Process Group is committed to providing you with the best support possible. Help is never more than a phone call away (or email if you prefer). Our people have many years of experience with ion beam sources, systems, and applications, and we're happy to share that with you. Give us a call.*

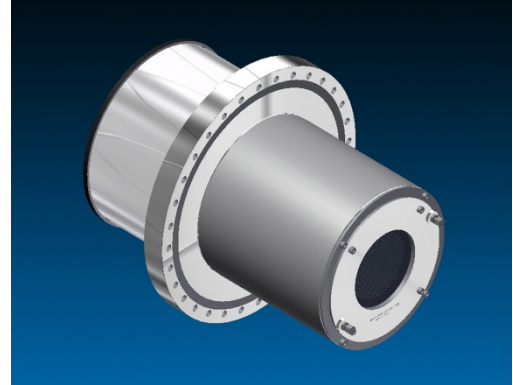
## Specifications

Internal Mount



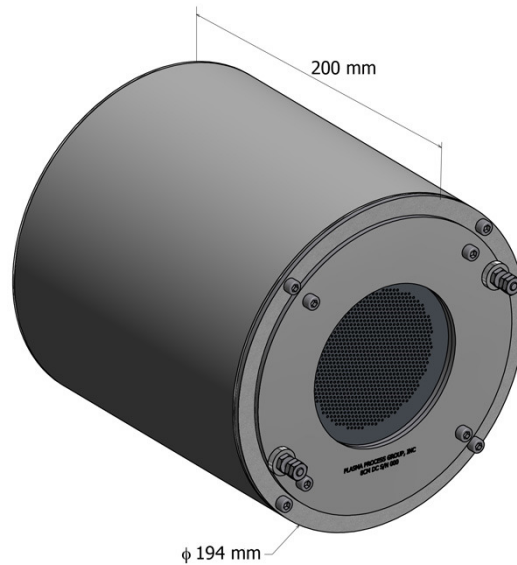
## 8 cm Source

Flange Mount (12" CF)



Ion source	8 cm DC
Model number	08DC04
Beam size at grids	8 cm
Beam current	25-250 mA
Beam energy	50-1500 eV
Grid material	Pyrolytic Graphite
Beam neutralization	Filament or PBN
Cooling	Radiant
Power supply	I-BEAM™ 601 or I-BEAM™ 602
Weight	5.9 Kg (13 lbs)

### Dimensions



**Ordering Information:** 8 cm ion beam sources are available with options such as internal or flange mounting kits to facilitate installation. Please contact us to configure your ion source.

### Suggested Accessories:

IBEAM 601 or IBEAM 602  
504138A  
504916A

I-BEAM™ 601 FC/FN Power Supply or I-BEAM™ 602 FC/PBN Power Supply  
Standard, 2-grid, Pyrolytic Graphite grid set for 8 cm Ion Source  
10" Conflat Flange Mount Interface Kit



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